

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Peter J. de Groot  
Serial No. : 10/659,060  
Filed : September 9, 2003  
Title : INTERFEROMETRY METHOD FOR ELLIPSOMETRY, REFLECTOMETRY, AND  
SCATTEROMETRY MEASUREMENTS, INCLUDING CHARACTERIZATION OF  
THIN FILM STRUCTURES

Art Unit : 2877  
Examiner : Unknown

Commissioner for Patents  
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SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Applicant submits the references listed on the attached form PTO-1449.

This statement is being filed within three months of the filing date of the application or before the receipt of a first Office action on the merits. Please apply any charges or credits to Deposit Account No. 06-1050, referencing Attorney Docket No. 09712-332001.

Respectfully submitted,

Date:

3/11/04

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**\*See attached document certifying that Marc M. Wefers has limited recognition to practice before the U.S. Patent and Trademark Office under 37 C.F.R. § 10.9(b).**

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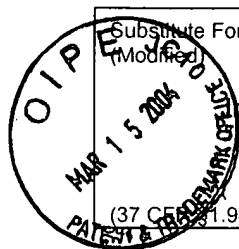
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U.S. Department of Commerce  
Patent and Trademark Office

Attorney's Docket No.

09712-332001

Application No.

10/659,060

**Information Disclosure Statement  
by Applicant**

(Use several sheets if necessary)

(37 C.F.R. 1.98(b))

Applicant

Peter J. de Groot

Filing Date

September 9, 2003

Group Art Unit

2877

**U.S. Patent Documents**

Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
	AA	4,999,014	03/12/1991	Gold et al.	356	382	
	AB	5,133,601	07/28/1992	Cohen et al.	356	359	
	AC	5,602,643	02/11/1997	Barrett	356	360	
	AD	6,545,763	04/08/2003	Kim et al.	356	503	
	AE	6,597,460	07/22/2003	Groot et al.	356	512	
	AF						
	AG						

**Foreign Patent Documents or Published Foreign Patent Applications**

Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
	AH							
	AI							

**Other Documents (include Author, Title, Date, and Place of Publication)**

Examiner Initial	Desig. ID	Document
	AJ	Dresel, Thomas et al., "Three-dimensional sensing of rough surfaces by coherence radar", <u>Applied Optics</u> , Vol. 31, No. 7, pp. 919-925 (March 1, 1992)
	AK	Feke, Gilbert D. et al., "Interferometric back focal plane microellipsometry", <u>Applied Optics</u> , Vol. 37, No. 10, pp. 1796-1802 (April 1, 1998)
	AL	Kim, Seung-Woo et al., "Thickness-profile measurement of transparent thin-film layers by white-light scanning interferometry", <u>Applied Optics</u> , Vol. 38, No. 28, pp. 5968-5973 (October 1, 1999)
	AM	Kino, Gordon S. et al., "Mirau correlation microscope", <u>Applied Optics</u> , Vol. 29, No. 26, pp. 3775-3783 (September 10, 1990)
	AN	Pelligrand, S. et al., "Mesures 3D de topographies et de vibrations a l'echelle (sub)micrometrique par microscopie optique interferometrique", <u>Proc. Club CMOI, Methodes et Techniques Optiques pour l'Industrie</u> (2002)
	AO	Pluta, Maksymilian, "Advanced Light Microscopy", Vol. 3, (Elsevier, Amsterdam, 1993) pp. 265-271
	AP	Rosencwaig, Allan et al., "Beam profile reflectometry: A new technique for dielectric film measurements", <u>Applied Physics Letters</u> , Vol. 60, No. 11, pp. 1301-1303 (March 16, 1992)
	AQ	Sandoz, Patrick "Wavelet transform as a processing tool in white-light interferometry", <u>Optics Letters</u> , Vol. 22, No. 14, pp. 1065-1067 (July 15, 1997)
	AR	Shatalin, S.V. et al., "Reflection conoscopy and micro-ellipsometry of isotropic thin film structures", <u>Journal of Microscopy</u> , Vol. 179, Part 3, pp. 241-252 (September, 1995)

Examiner Signature

Date Considered

EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.